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(CMM), Reprinted from: Appl. Sci. 2016, 6(7), 202, <http://www.mdpi.com/2076-3417/6/7/20297> -- So Ito, Hirotaka Kikuchi, Yuanliu Chen, Yuki Shimizu, Wei Gao, Kazuhiko Takahashi, Toshihiko Kanayama, Kunmei Arakawa and Atsushi Hayashi A Micro-Coordinate Measurement Machine (CMM) for Large-Scale Dimensional Measurement of Micro-Slits, Reprinted from: Appl. Sci. 2016, 6(5), 156, <http://www.mdpi.com/2076-3417/6/5/156112> -- Hiroshi Murakami, Akio Katsuki, Takao Sajima and Mitsuyoshi Fukuda Reduction of Liquid Bridge Force for 3D Microstructure Measurements, Reprinted from: Appl. Sci. 2016, 6(5), 153, <http://www.mdpi.com/2076-3417/6/5/153139> -- Rui-Jun Li, Meng Xiang, Ya-Xiong He, Kuang-Chao Fan, Zhen-Ying Cheng, Qiang-Xian Huang and Bin Zhou Development of a High-Precision Touch-Trigger Probe Using a Single Sensor, Reprinted from: Appl. Sci. 2016, 6(3), 86, <http://www.mdpi.com/2076-3417/6/3/86153> -- Adam Gaska, Piotr Gaska and Maciej Gruza Simulation Model for Correction and Modeling of Probe Head Errors in Five-Axis Coordinate Systems, Reprinted from: Appl. Sci. 2016, 6(7), 190, <http://www.mdpi.com/2076-3417/6/7/190>.

Sommario/riassunto

Coordinate measuring machines (CMMs) have been conventionally used in industry for 3-dimensional and form-error measurements of macro parts for many years. Ever since the first CMM, developed by Ferranti Co. in the late 1950s, they have been regarded as versatile measuring equipment, yet many CMMs on the market still have inherent systematic errors due to the violation of the Abbe Principle in its design. Current CMMs are only suitable for part tolerance above 10 m. With the rapid advent of ultraprecision technology, multi-axis machining, and micro/nanotechnology over the past twenty years, new types of ultraprecision and micro/nano-CMMs are urgently needed in all aspects of society. This Special Issue accepted papers revealing novel designs and applications of CMMs, including structures, probes, miniaturization, measuring paths, accuracy enhancement, error compensation, etc. Detailed design principles in sciences, and technological applications in high-tech industries, were required for submission. Topics covered, but were not limited to, the following areas: 1. New types of CMMs, such as Abbe-free, multi-axis, cylindrical, parallel, etc. 2. New types of probes, such as touch-trigger, scanning, hybrid, non-contact, microscopic, etc. 3. New types of Micro/nano-CMMs. 4. New types of measuring path strategy, such as collision avoidance, free-form surface, aspheric surface, etc. 5. New types of error compensation strategy.